

INFORMATION DISCLOSURE STATEMENT BY APPLICANT



Complete Known

Application Number	10/084,622
Filing Date	February 28, 2002
First Named Inventor	Kyoungdoug MIN, et al.
Group Art Unit	
Examiner Name	
Attorney Docket Number	1751-300

Sheet 1 of 1

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
JD	1	A.A. AYON, et al., "Characterization of a Time Multiplexed Inductively Coupled Plasma Etcher", <u>Journal of the Electrochemical Society</u> , 1999, 339-349 pp., vol 146 (1), The Electrochemical Society, Inc., Cambridge, Massachusetts, USA.	
	2	LUC G. FRECHETTE, et al., "Demonstration of a Microfabricated High-Speed Turbine Supported on Gas Bearings", <u>Solid-State Sensor and Actuator Workshop Hilton Head Is., SC</u> , June 4-8, 2000, 1-5 pp., Gas Turbine Laboratory and Microsystems Technology Laboratories Massachusetts Institute of Technology, Cambridge, Massachusetts, USA.	
	3	RAVI KHANNA, et al., "Microfabrication Protocols for Deep Reactive Ion Etching and Wafer-Level Bonding", <u>MicroStrain Materials Science</u> , Sensors Online.	
JD	4	Amit Mehra, et al., " A Six-Wafer Combustion System for a Silicon Micro Gas Turbine Engine", <u>Journal of Microelectromechanical systems</u> , December 2000, 517-527pp, vol. 9, no. 4, IEEE.	

Examiner Signature	JD	Date Considered	3/15/04
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.